

Electronic Patent Application Fee Transmittal

Application Number:	09991196			
Filing Date:	20-Nov-2001			
Title of Invention:	HIGH DENSITY PLASMA CHEMICAL VAPOR DEPOSITION PROCESS			
First Named Inventor/Applicant Name:	Chih-Chien Liu			
Filer:	William H. Wright/Vivian Gutierrez			
Attorney Docket Number:	UMC-96-279 CON2			
Filed as Large Entity				
Utility Filing Fees				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
Pages:				
Claims:				
Miscellaneous-Filing:				
Petition:				
Patent-Appeals-and-Interference:				
Post-Allowance-and-Post-Issuance:				
Statutory disclaimer	1814	1	130	130
Extension-of-Time:				

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Extension - 2 months with \$0 paid	1252	1	460	460
Miscellaneous:				
Request for continued examination	1801	1	810	810
Total in USD (\$)				1400